

	Type	L #	Hits	Search Text	DBs
1	BRS	L1	16488	lithography and wafer and substrate	USPAT; US-PGPUB
2	BRS	L2	7334	1 and plasma	USPAT; US-PGPUB
3	BRS	L3	5925	2 and (mask reticle)	USPAT; US-PGPUB
4	BRS	L4	525	3 and (vacuum adj chamber)	USPAT; US-PGPUB
5	BRS	L5	0	4 and (transport adj chamber)	USPAT; US-PGPUB
6	BRS	L6	10	4 and (transport adj system)	USPAT; US-PGPUB